Form	PTO-144	19	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE					ATTY. DOCKET N MI22-2383		Priority SERIAL NO. 10/271.888			
			LIS.		ART CITED BY APPLICANT (se several sheets if necessary)			APPLICANT Fernando Gonzalez					
ja			, "			Priority FILING D. October 15, 2002		ATE Priori		iy GROUP			
U.S. PATENT DOCUMENTS													
*Exam Init			Document Number		Date	Name		Class	Subclass	Filing D: If Appropr			
4_		AA	6,309,945 B1		10/01	Sato et al.		-					
		АВ	5,298,449		03/94	Kikuchi							
	-	AC	5,374	,564	12/94	Bruel	iruel						
		AD	5,855,693		01/99	Murari et al.							
		AE	E 5,877,070		03/99	Guesele et al.							
		AF	5,882,987		03/99	Srikrishnan							
		AG	5,894,152		04/99	Jaso et al.							
		AH	5,953,622		09/99	Lee et al.							
		Al	6,004,406		12/99	Kobayashi et al.							
		Ŋ	6,251,754		6/01	Ohshima et al.		-					
		AK		,161	6/01	Henley et al.							
		AL	5,374,581		12/94	Ichikawa et al.							
		AM	4,891,329		1/90	Reisman et al.							
		AN	6,150,031		11/00	Yonehara							
		AO	6,083,324		7/00	Henley et al.							
		AP	6,309,945		10-2001	Sato et al.							
		AQ	6,423,992 B2		07/02	Fukuda et al.						_	
-		AR	6,384,439 B1		05/02	Walker							
ci		AS 5,998.847		.847	12/99	Assaderaghi et al.				,			
FOREIGN PATENT DOCUMENTS													
			Document Number		Date		Country		Class	Subclass	Translat		
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)												ייי	
Q_		AT		Gösele. U. et al., "Semiconductor Wafer Bonding: Science, Technology, and Applications". Electrochemical Society Proceedings									
		Vol. 97-36, (@1998), pp. 400-425, 436-445.											
EXAMINER Calvula DATE CONSIDERED 6. 7								7. 04	φ				
	*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.												

age of the